The 15th Micromachine Exhibition: "Micromachine 2004"

The 15th Micromachine Exhibition, "Micromachine 2004," was held in conjunction with The 10th International Micromachine/Nanotech Symposium at the Science Museum in Kitanomaru Park, Tokyo, for 3 days from November 10 to 12, 2004, and was a roaring success.

The theme for this year's exhibition was "Limitless Business Fields Opened up by Micro/Nano Technology: International Exhibition on Micro-Ultraprecision/Microfabrication, MEMS, Nanotechnology, and Biotechnology".

In addition to the Micromachine Center and 11 of its supporting member organizations, generous cooperation in the arrangement of exhibitions was also provided by private businesses, universities, and independent public organizations. A total of 247 displays (352 booths) were exhibited by representatives of various businesses, academic groups, universities, and research organizations. France's National Center for Scientific Research (*Centre National de la Recherche Scientifique*) and six other organizations from abroad also presented exhibits.

In accordance with the increased number of exhibitors, the Micromachine 2004 exhibition occupied, for the first time, the entire first floor hall space and preparation room, a part of the lounge, and a part of the second floor, of the Science Museum.

Furthermore, a total of 77 businesses and academic groups took part in the exhibition, including 2 companies participating from abroad for the first time, and a wide range of new technologies and products in the fields of nano-technology and micromachines were presented.

Thanks in part to the exhibition being held in $10^{\rm th}$ conjunction International with the Micromachine/Nanotech Symposium, an attendance of 8,213 people was achieved over the three days of the event. Researchers, engineers, and administrators from the frontlines of various technological fields accounted for a large number of these attendees, and through the exchange of ideas and sharing of research information with colleagues from other fields, the exhibition provided an ideal opportunity for discussion of the possibilities for new technologies and to resolve a wide range of developmental issues.

SUNTEN BHI - MING MAYOURS SHEET

The exhibition hall, packed with attendees.

The main products displayed at the exhibition included micromachines, their associated components and application systems, MEMS-related systems, nanotechnologies and materials, technologies related to microultraprecision fabrication and production, equipment, biotechnology and medical systems, evaluation and measurement devices, and software. In this regard, Micromachine 2004 was ideally suited to researchers, engineers, designers, manufacturers, and managers from fields such as mechanisms and precision machinery; electrical devices and electronics, medicine; information technology; automobiles and transportation; biology, physics, and chemistry; architecture; metallurgy; space aviation; and shipping and oceanography.

Furthermore, the exhibition provided an excellent opportunity for the promotion of technologies, devices, and products by businesses in the field of micromachine research and development; for the presentation of the results of research projects by universities and other research organizations; and for the announcement of products and technologies by other newly participating businesses.

On its opening day, the exhibition was visited by Mr. Sakae Takahashi, Executive Director of NEDO (independent administrative organization), who spoke at the reception that was held following the exhibition. On the second day, it was also visited by Mr. Yoshinori Komiya, Director of the Industrial Machinery Division, Manufacturing Industries Bureau, METI.

Micromachine 2005 will be held from November 9 (Wednesday) to 11 (Friday), 2005 at the Science Museum, Kitanomaru Park, Tokyo.

Inquiries: Mesago Messe Frankfurt Corporation

T e I: 0 3 - 3 2 6 2 - 8 4 4 1

F a **x**: 0 3 - 3 2 6 2 - 8 4 4 2

Email: info@micromachine.jp

U R L: http://www.micromachine.jp



Attendees at the post-exhibition reception.